

*Supplementary Information*

# Fabrication and Characterization of Hybrid and Tunable ZnO@Ag Flexible Thin Films Used as SERS Substrates

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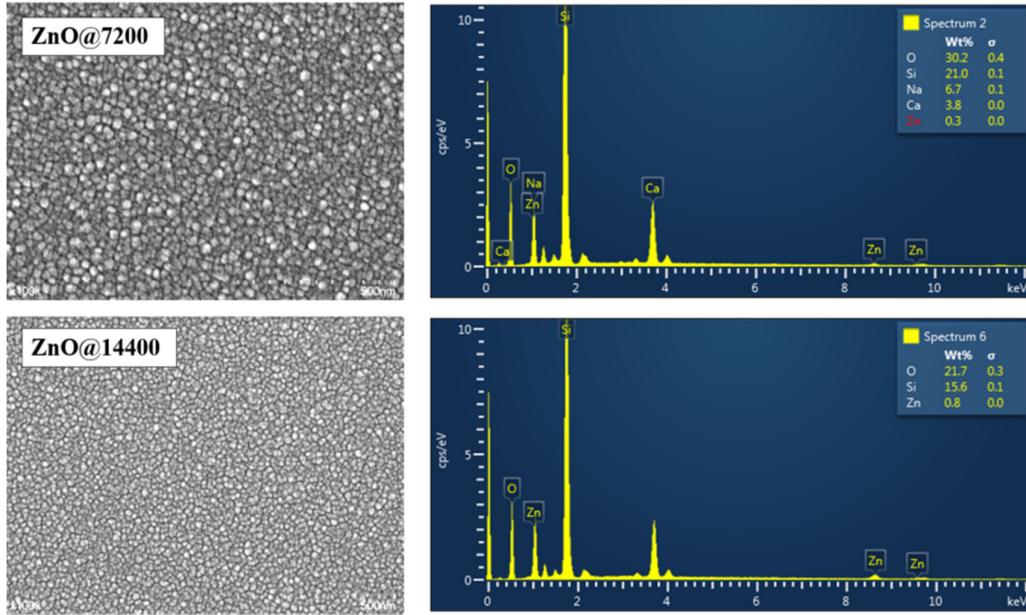
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Substrate	Deposition time (min)	Abbreviation		Final substrate temperature (°C)
Zeonor	15			27
	30			27
	60			30
Topas	15			25
	30			25
	60			28
Topas@2	15			27
	30			27
	60			29

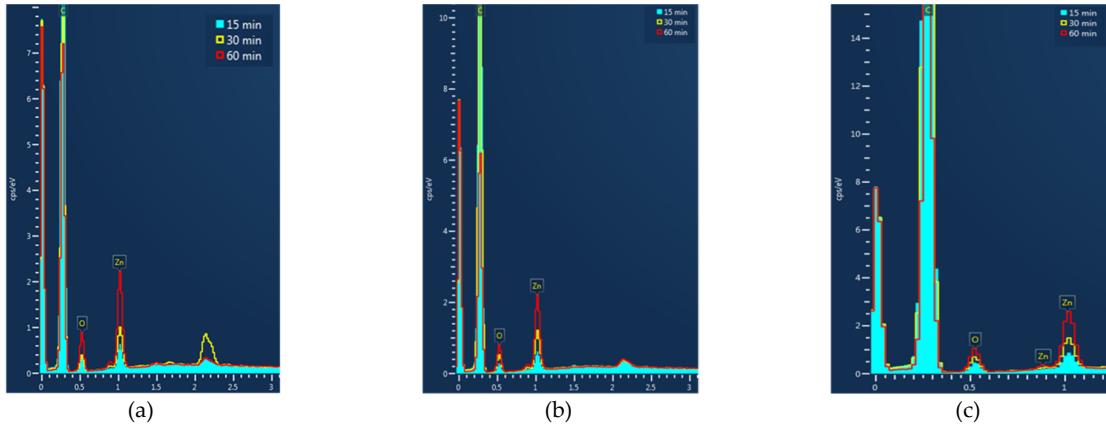
**Table S1** – The detailed parameters of MS deposition at RT for ZnO thin films.



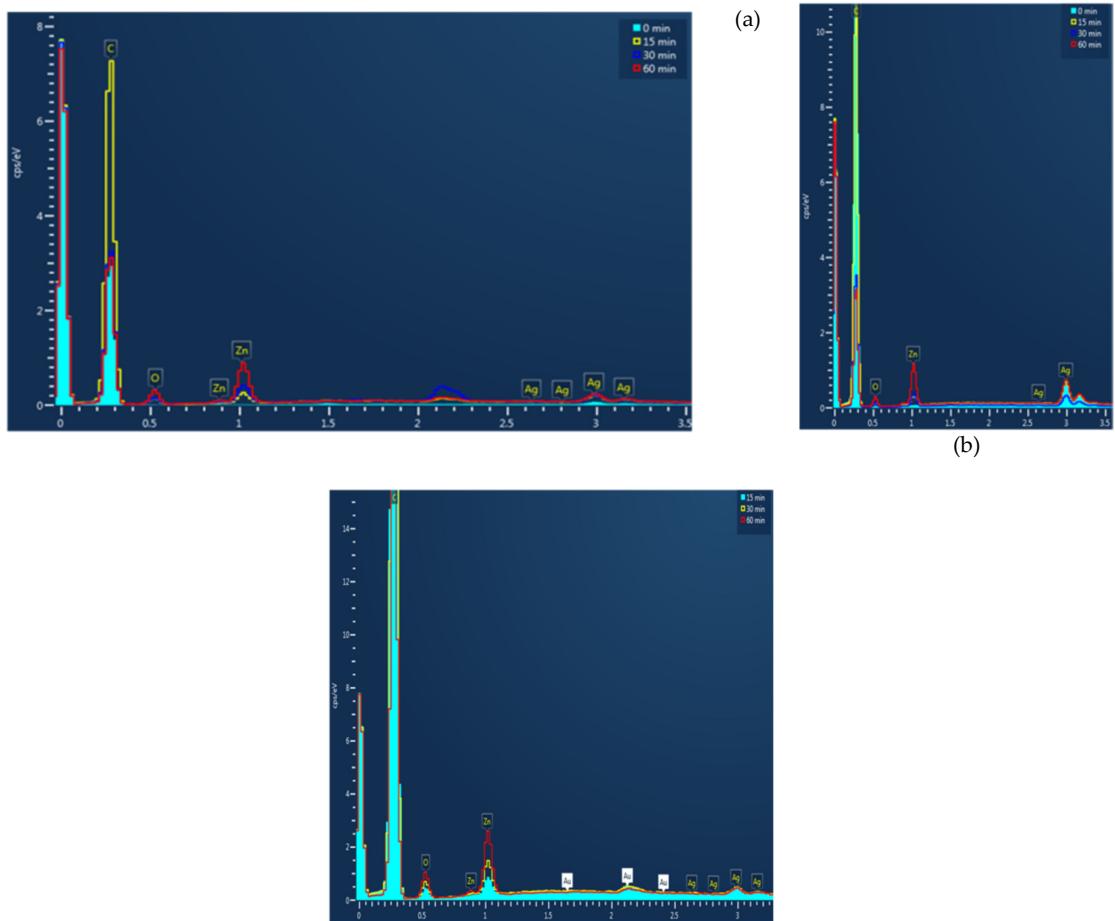
**Figure S1.** Representative SEM images (left) and EDX spectra (right) of ZnO films deposited on glass by PLD at RT in O<sub>2</sub> bleeding gas and a number of laser pulses of 7200 and 14400, respectively. The growth mode of the films is similar to that of the MS deposited films on Zeonor® and Topas® with a granular structure without defects or voids. This may also be due to the fact that both glass and polymer films have an amorphous structure. EDX spectra show the amount of O and Zn present in the deposited films. Along with the increase of the number of laser pulses, there was a slight increase in the Zn content.

**Table S2.** – The detailed parameters of MS deposition at RT for Ag thin films on top of ZnO nanostructures.

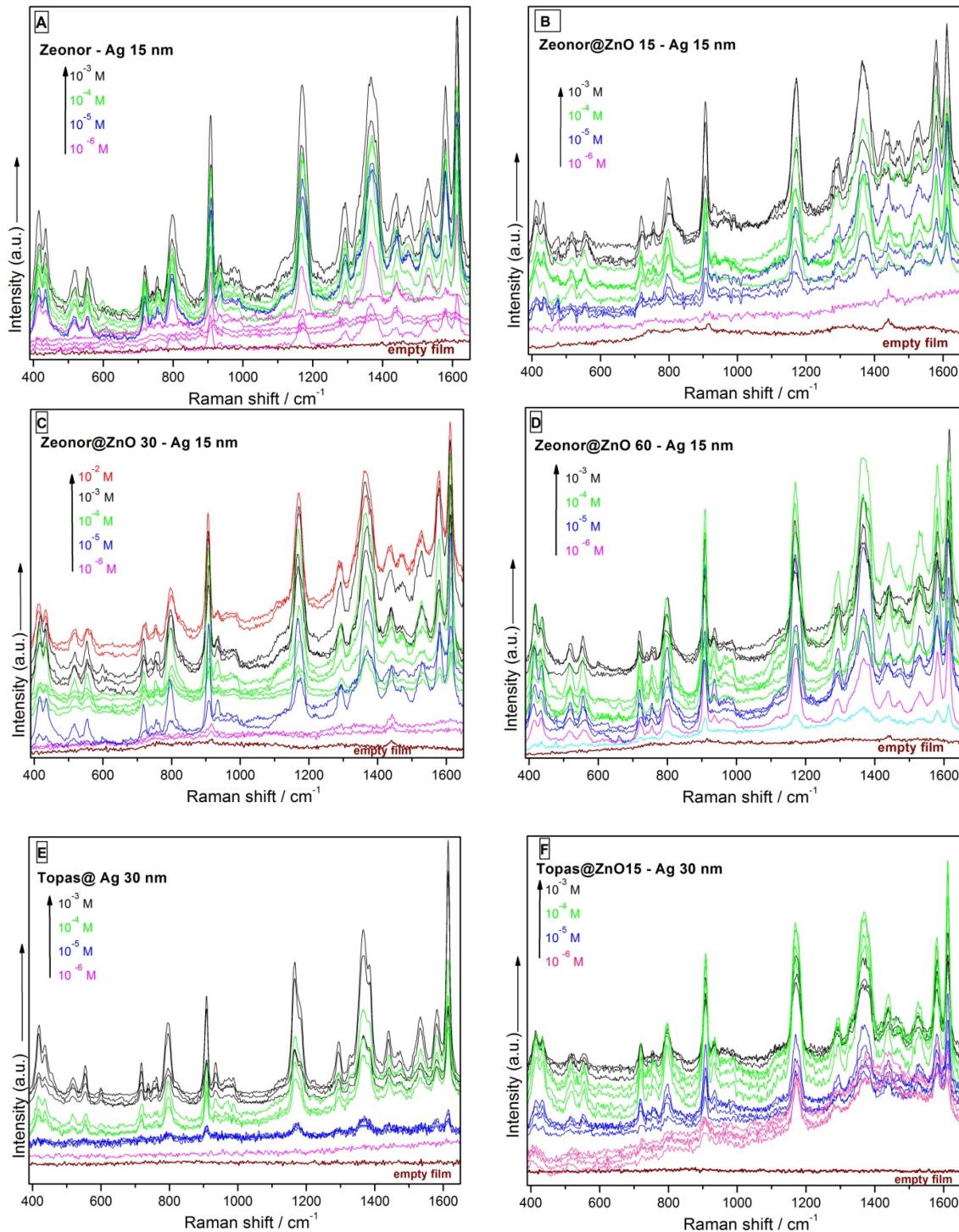
Substrate	Ag film thickness (nm)	Deposition rate (nm/min)	Current (mA)	Rotation (nm/min)	Abbreviation
Zeonor					Zeonor@Ag
Zeonor@15					Zeonor15@Ag
Zeonor@30	15				Zeonor30@Ag
Zeonor@60					Zeonor60@Ag
Topas					Topas@Ag
Topas@15					Topas15@Ag
Topas@30	30	7	35	5	Topas30@Ag
Topas@60					Topas60@Ag
Topas2					Top@Ag
Topas2@15					Top15@Ag
Topas2@30	7				Top30@Ag
Topas2@60					Top60@Ag

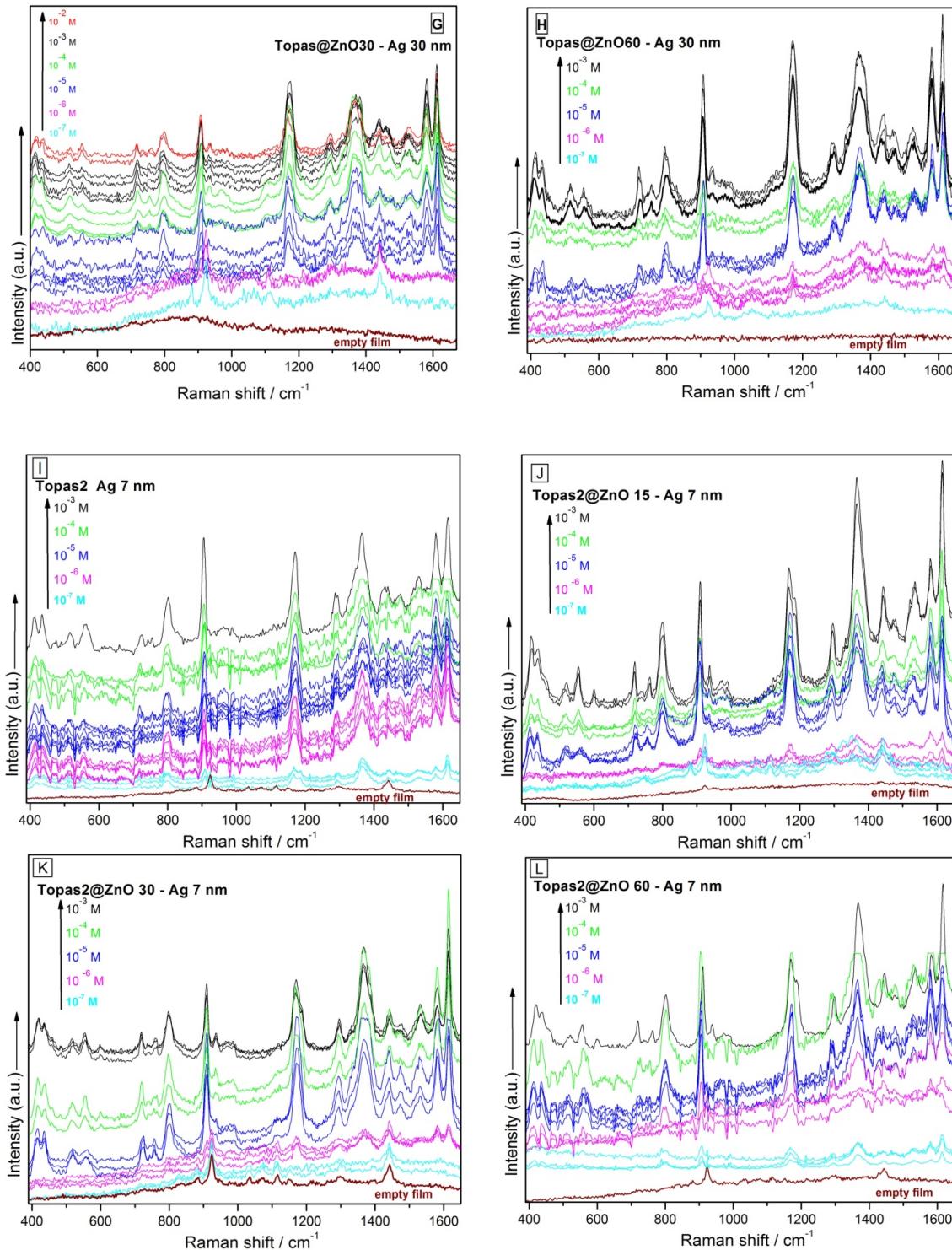


**Figure S2.** Comparative EDX spectra confirming the film growth and proportional increasing of Zn and O elements in concordance with the increasing deposition time in the ZnO films deposited on (a) Zeonor, (b) Topas® and (c) Topas@2.

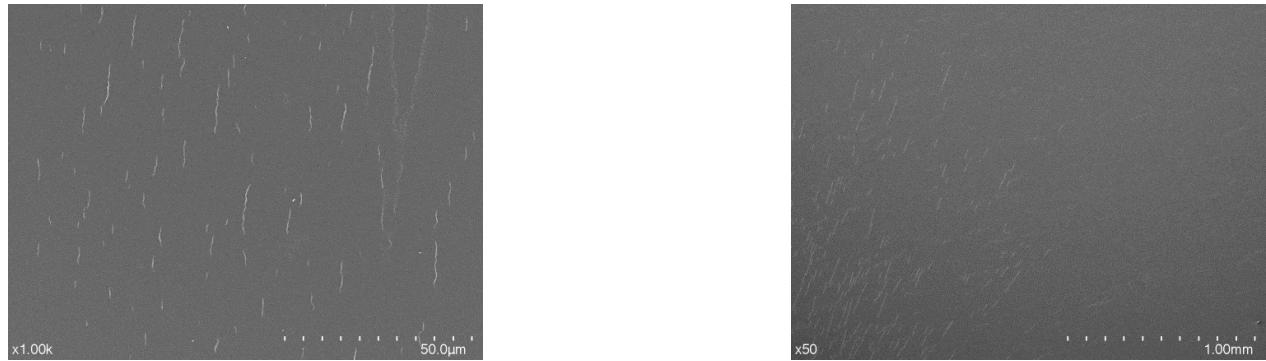


**Figure S3.** Comparative EDX spectra confirming the Ag film growth and proportional increasing of Ag element in the hybrid samples on (a) Zeonor, (b) Topas® and (c) Topas@2.

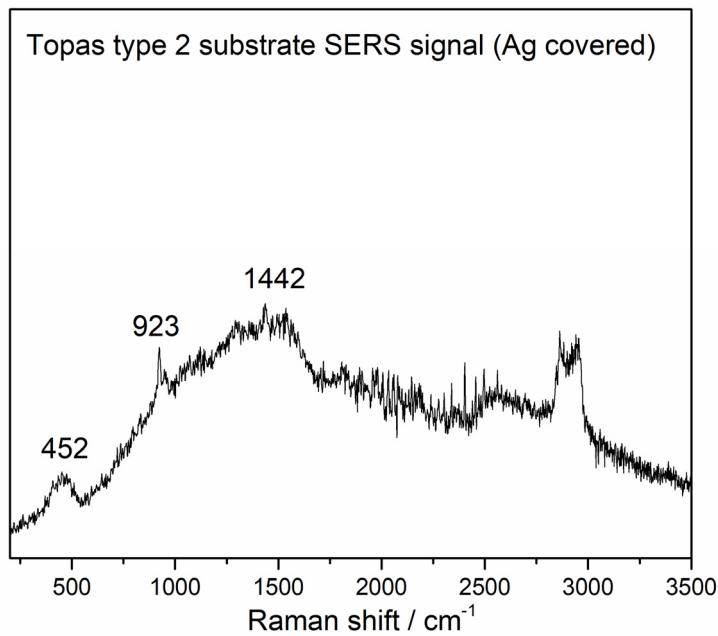




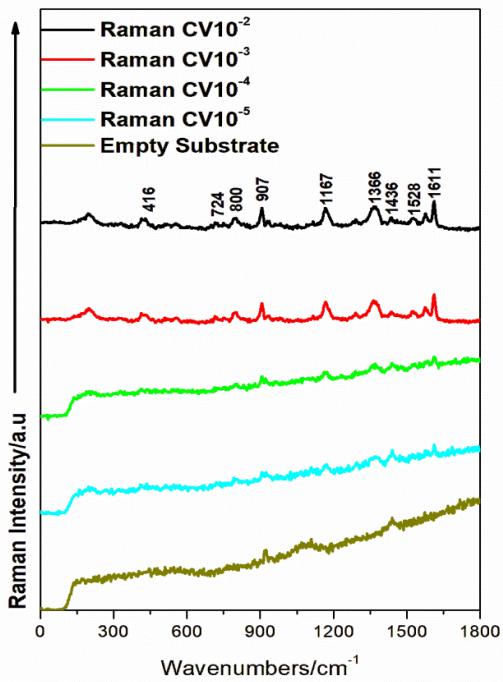
**Figure S4.** Comparative SERS spectra showing the reproducibility of the fingerprint of CV aqueous solutions on Zeonor® (A-D), Topas® (E-H) and Topas type 2 (I-L). All SERS spectra were measured using a laser power of 5 mW, 10 s/accumulation and 2 accumulations/spectrum.



**Figure S5.** SEM micrographs showing defects in Topas@30 (left) and Topas@60 (right) samples.



**Figure S6.** Representative SERS signal from the Topas type 2 substrate obtained after Ag thin film deposition.



**Figure S7.** Representative Raman signal of CV aqueous solution of different concentrations on Zeonor® in comparison with the empty plastic substrate Raman signal.